PLUS

	L #	Hits	Search T xt	DBs	Tim Stamp	Type
1	L1	50	("4294404" "5778075" "5794147" "5870673" "6285881" "6792323" "4761641" "5826117" "5850577" "5305037" "5504935" "4509842" "5371566" "6144312" "4403285" "4425531" "4793980" "4805112" "4827410" "4835679" "4918379" "4971796" "5177524" "5267085" "5339126" "5392159" "5392502" "5442779" "5522028" "5568545" "5663954" "5692223" "5740070" "5844805" "5966550" "5986586" "6021514" "6034723" "6041515" "6209034" "6241456" "6247028" "6339670" "6407417" "6409198" "6457654" "4281775" "4246776" "4261132" "4335376").pn.	USPAT	2004/12/12 10:03	BRS

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Most Frequently Occurring Classifications of Patents Returned
From A Search of 10749698 on November 26, 2004

Original Classifications
2 455/434

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3 455/552.1
2 345/179
2 359/705
2 359/823
2 375/216
2 396/89
2 455/454
2 455/67.11

Combined Classifications
3 455/434
3 455/552.1
2 345/179
2 359/694
2 359/705
2 359/823
2 375/216
2 396/103
2 396/79
2 396/82
2 396/85
2 396/89
2 455/454
2 455/67.11
2 700/180

EAST

	L #	Hits	Search Text	DBs	Tim Stamp	Type
1	L1	67305	process ADJ control	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/12 10:21	BRS
2	L2	426	L1 SAME recipe	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/12 10:21	BRS
3	L3	116	L2 SAME (prior OR past OR feedback OR feed ADJ back OR histor$ OR previous$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/12 10:25	BRS
4	L4	569	RBR OR "run-by -run"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/12 12:28	BRS
5	L5	1	L3 AND L4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/12 10:25	BRS
6	L6	73	L4 SAME (prior OR past OR feedback OR feed ADJ back OR histor$ OR previous$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/12 10:26	BRS
7	L7	115	L3 NOT (L5 OR L6)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/12 10:26	BRS
8	L8	12	("6249712").URPN.	USPAT	2004/12/12 11:35	BRS
9	L10	296	L4 NOT (L5 OR L6 OR L7 OR L8)	USPAT	2004/12/12 12:28	BRS
10	L11	10	("6587744").URPN.	USPAT	2004/12/12 11:53	BRS
11	L12	41	("5926690").URPN.	USPAT	2004/12/12 12:05	BRS
12	L13	0	("6625513").URPN.	USPAT	2004/12/12 12:08	BRS
13	L14	686	"run-by-run" OR "run-to-run"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/12 12:28	BRS
14	L15	424	L14 NOT (L5 OR L6 OR L7 OR L8 OR L10 OR L11 OR L12)	USPAT	2004/12/12 12:29	BRS
15	L16	160	L15 AND (L1 OR recipe)	USPAT	2004/12/12 12:29	BRS

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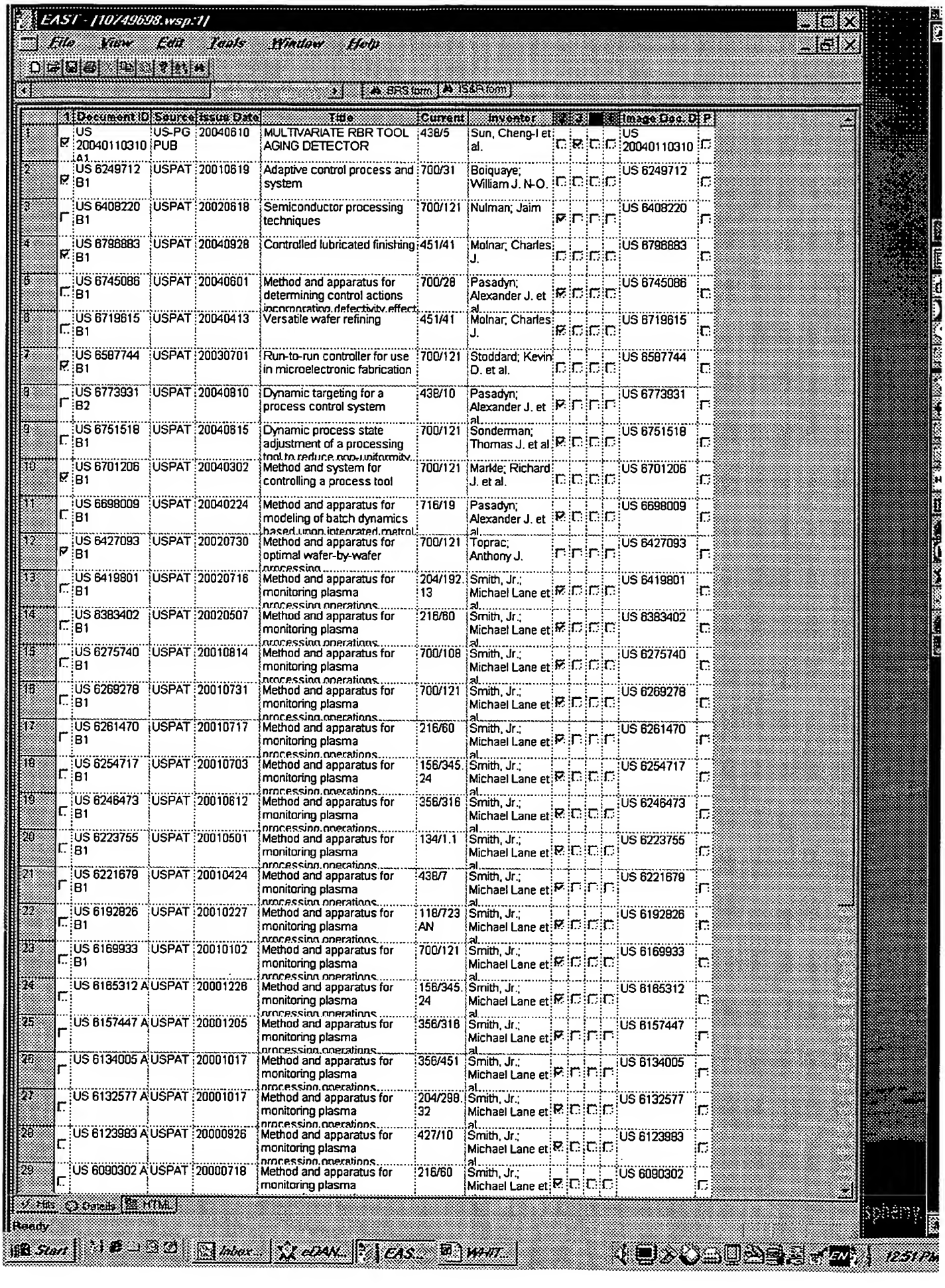
EAST - [10749698.wsp:7]
File View Edit Tools Window Help
BRS form
IS&R form
1 Document ID Source Issue Date Title Current Inventor 2 3 4 5 Image Doc. ID P
1 US 20040110310 A1 US-PG PUB 20040610 MULTIVARIATE RBR TOOL AGING DETECTOR 438/5 Sun, Cheng-I et al. US 20040110310
2 US 6249712 B1 USPAT 20010619 Adaptive control process and system 700/31 Boiquaye; William J. N-O. US 6249712
3 US 6408220 B1 USPAT 20020618 Semiconductor processing techniques 700/121 Nulman; Jaim US 6408220
4 US 6786883 B1 USPAT 20040928 Controlled lubricated finishing 451/41 Molnar; Charles J. US 6786883
5 US 6745086 B1 USPAT 20040601 Method and apparatus for determining control actions incorporating defectivity effect 700/28 Pasadyn; Alexander J. et al. US 6745086
6 US 6719615 B1 USPAT 20040413 Versatile wafer refining 451/41 Molnar; Charles J. US 6719615
7 US 6587744 B1 USPAT 20030701 Run-to-run controller for use in microelectronic fabrication 700/121 Stoddard; Kevin D. et al. US 6587744
8 US 6773931 B2 USPAT 20040810 Dynamic targeting for a process control system 438/10 Pasadyn; Alexander J. et al. US 6773931
9 US 6751518 B1 USPAT 20040615 Dynamic process state adjustment of a processing tool to reduce non-uniformity 700/121 Sonderman; Thomas J. et al. US 6751518
10 US 6701206 B1 USPAT 20040302 Method and system for controlling a process tool 700/121 Markle; Richard J. et al. US 6701206
11 US 6698009 B1 USPAT 20040224 Method and apparatus for modeling of batch dynamics based upon integrated metrol 716/19 Pasadyn; Alexander J. et al. US 6698009
12 US 6427093 B1 USPAT 20020730 Method and apparatus for optimal wafer-by-wafer processing 700/121 Toprac; Anthony J. US 6427093
13 US 6419801 B1 USPAT 20020716 Method and apparatus for monitoring plasma processing operations 204/192.13 Smith, Jr.; Michael Lane et al. US 6419801
14 US 6383402 B1 USPAT 20020507 Method and apparatus for monitoring plasma processing operations 216/60 Smith, Jr.; Michael Lane et al. US 6383402
15 US 6275740 B1 USPAT 20010814 Method and apparatus for monitoring plasma processing operations 700/108 Smith, Jr.; Michael Lane et al. US 6275740
16 US 6269278 B1 USPAT 20010731 Method and apparatus for monitoring plasma processing operations 700/121 Smith, Jr.; Michael Lane et al. US 6269278
17 US 6261470 B1 USPAT 20010717 Method and apparatus for monitoring plasma processing operations 216/60 Smith, Jr.; Michael Lane et al. US 6261470
18 US 6254717 B1 USPAT 20010703 Method and apparatus for monitoring plasma processing operations 156/345.24 Smith, Jr.; Michael Lane et al. US 6254717
19 US 6246473 B1 USPAT 20010612 Method and apparatus for monitoring plasma processing operations 356/316 Smith, Jr.; Michael Lane et al. US 6246473
20 US 6223755 B1 USPAT 20010501 Method and apparatus for monitoring plasma processing operations 134/1.1 Smith, Jr.; Michael Lane et al. US 6223755
21 US 6221679 B1 USPAT 20010424 Method and apparatus for monitoring plasma processing operations 438/7 Smith, Jr.; Michael Lane et al. US 6221679
22 US 6192826 B1 USPAT 20010227 Method and apparatus for monitoring plasma processing operations 118/723 AN Smith, Jr.; Michael Lane et al. US 6192826
23 US 6169933 B1 USPAT 20010102 Method and apparatus for monitoring plasma processing operations 700/121 Smith, Jr.; Michael Lane et al. US 6169933
24 US 6165312 A USPAT 20001226 Method and apparatus for monitoring plasma processing operations 156/345.24 Smith, Jr.; Michael Lane et al. US 6165312
25 US 6157447 A USPAT 20001205 Method and apparatus for monitoring plasma processing operations 356/318 Smith, Jr.; Michael Lane et al. US 6157447
26 US 6134005 A USPAT 20001017 Method and apparatus for monitoring plasma processing operations 356/451 Smith, Jr.; Michael Lane et al. US 6134005
27 US 6132577 A USPAT 20001017 Method and apparatus for monitoring plasma processing operations 204/298.32 Smith, Jr.; Michael Lane et al. US 6132577
28 US 6123983 A USPAT 20000926 Method and apparatus for monitoring plasma processing operations 427/10 Smith, Jr.; Michael Lane et al. US 6123983
29 US 6090302 A USPAT 20000718 Method and apparatus for monitoring plasma 216/60 Smith, Jr.; Michael Lane et US 6090302
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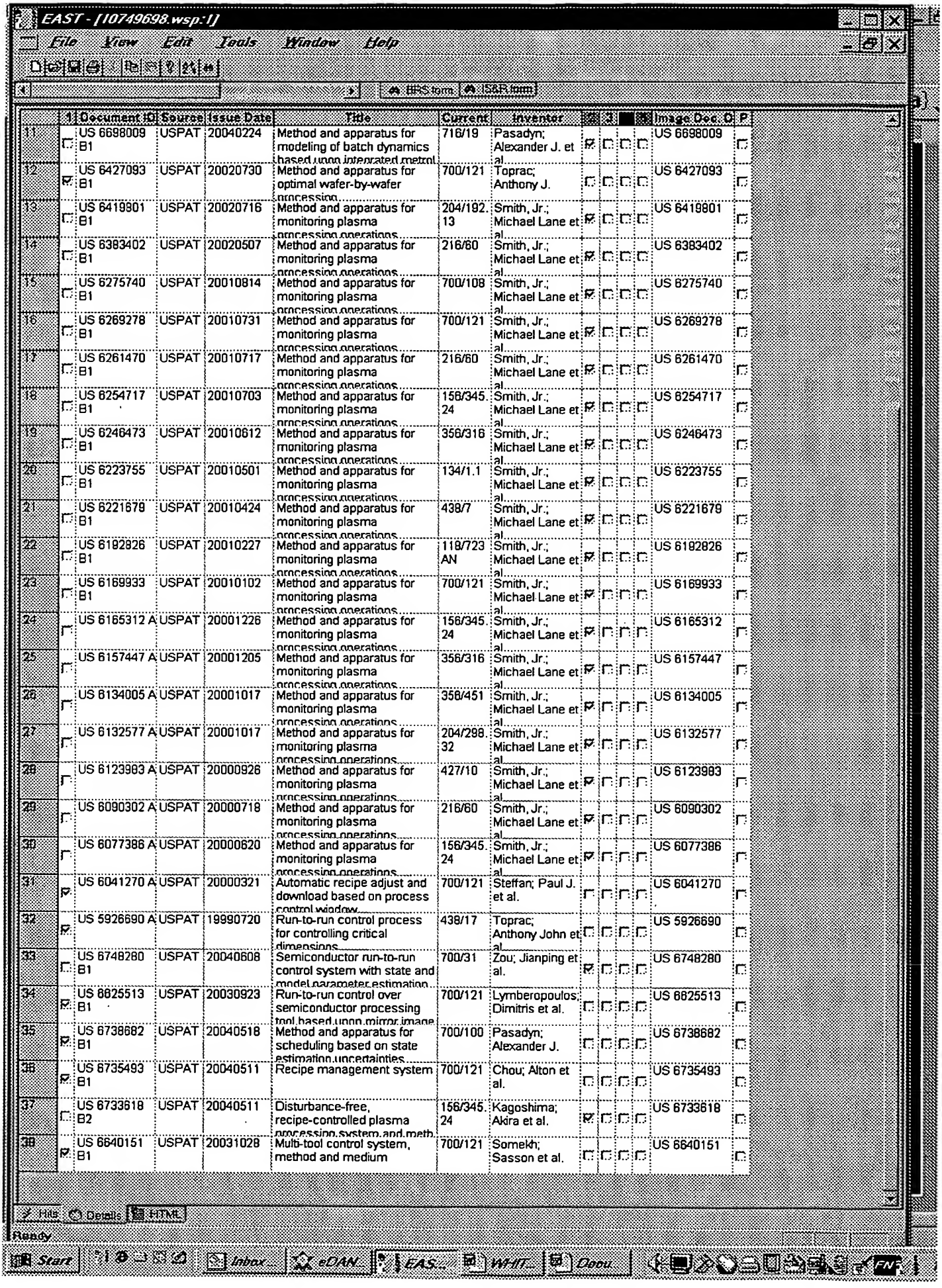
EAST - [10749698.wsp:1]
File View Edit Tools Window Help
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IS&R form
1 Document ID Source Issue Date Title Current Inventor 3 Image Doc ID P
11 US 6698009 B1 USPAT 20040224 Method and apparatus for modeling of batch dynamics based upon integrated metrol 716/19 Pasadyn; Alexander J. et al. US 6698009
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14 US 6383402 B1 USPAT 20020507 Method and apparatus for monitoring plasma processing operations 216/60 Smith, Jr.; Michael Lane et al. US 6383402
15 US 6275740 B1 USPAT 20010814 Method and apparatus for monitoring plasma processing operations 700/108 Smith, Jr.; Michael Lane et al. US 6275740
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17 US 6261470 B1 USPAT 20010717 Method and apparatus for monitoring plasma processing operations 216/60 Smith, Jr.; Michael Lane et al. US 6261470
18 US 6254717 B1 USPAT 20010703 Method and apparatus for monitoring plasma processing operations 156/345.24 Smith, Jr.; Michael Lane et al. US 6254717
19 US 6246473 B1 USPAT 20010612 Method and apparatus for monitoring plasma processing operations 356/316 Smith, Jr.; Michael Lane et al. US 6246473
20 US 6223755 B1 USPAT 20010501 Method and apparatus for monitoring plasma processing operations 134/1.1 Smith, Jr.; Michael Lane et al. US 6223755
21 US 6221679 B1 USPAT 20010424 Method and apparatus for monitoring plasma processing operations 438/7 Smith, Jr.; Michael Lane et al. US 6221679
22 US 6192826 B1 USPAT 20010227 Method and apparatus for monitoring plasma processing operations 118/723 AN Smith, Jr.; Michael Lane et al. US 6192826
23 US 6169933 B1 USPAT 20010102 Method and apparatus for monitoring plasma processing operations 700/121 Smith, Jr.; Michael Lane et al. US 6169933
24 US 6165312 A USPAT 20001226 Method and apparatus for monitoring plasma processing operations 156/345.24 Smith, Jr.; Michael Lane et al. US 6165312
25 US 6157447 A USPAT 20001205 Method and apparatus for monitoring plasma processing operations 356/316 Smith, Jr.; Michael Lane et al. US 6157447
26 US 6134005 A USPAT 20001017 Method and apparatus for monitoring plasma processing operations 356/451 Smith, Jr.; Michael Lane et al. US 6134005
27 US 6132577 A USPAT 20001017 Method and apparatus for monitoring plasma processing operations 204/298.32 Smith, Jr.; Michael Lane et al. US 6132577
28 US 6123983 A USPAT 20000926 Method and apparatus for monitoring plasma processing operations 427/10 Smith, Jr.; Michael Lane et al. US 6123983
29 US 6090302 A USPAT 20000718 Method and apparatus for monitoring plasma processing operations 216/60 Smith, Jr.; Michael Lane et al. US 6090302
30 US 6077386 A USPAT 20000620 Method and apparatus for monitoring plasma processing operations 156/345.24 Smith, Jr.; Michael Lane et al. US 6077386
31 US 6041270 A USPAT 20000321 Automatic recipe adjust and download based on process control window 700/121 Steffan; Paul J. et al. US 6041270
32 US 5926690 A USPAT 19990720 Run-to-run control process for controlling critical dimensions 438/17 Toprac; Anthony John et al. US 5926690
33 US 6748280 B1 USPAT 20040608 Semiconductor run-to-run control system with state and model parameter estimation 700/31 Zou; Jianping et al. US 6748280
34 US 6625513 B1 USPAT 20030923 Run-to-run control over semiconductor processing tool based upon mirror image 700/121 Lymberopoulos; Dimitris et al. US 6625513
35 US 6738682 B1 USPAT 20040518 Method and apparatus for scheduling based on state estimation uncertainties 700/100 Pasadyn; Alexander J. US 6738682
36 US 6735493 B1 USPAT 20040511 Recipe management system 700/121 Chou; Alton et al. US 6735493
37 US 6733618 B2 USPAT 20040511 Disturbance-free, recipe-controlled plasma processing system and meth 156/345.24 Kagoshima; Akira et al. US 6733618
38 US 6640151 B1 USPAT 20031028 Multi-tool control system, method and medium 700/121 Somekh; Sasson et al. US 6640151
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